

WHAT IS CLAIMED IS:

1. A method of manufacturing a structure with pores, comprising the steps of:

(A) disposing a lamination film on a substrate,  
5 the lamination film comprising insulating layers and a layer to be anodically oxidized and containing aluminum as a main composition; and

(B) performing anodic oxidation starting from an end surface of the lamination film to form a plurality  
10 of pores having an axis substantially parallel to a surface of the substrate,

wherein the layer to be anodically oxidized is sandwiched between the insulating layers, and a projected pattern substantially parallel to the axis of  
15 the pores is formed on at least one of the insulating layers at positions between the pores.

2. A method according to claim 1, wherein the layer to be anodically oxidized is made of aluminum.

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3. A method according to claim 1, wherein at least one of the insulating layers is formed by anodic oxidation.

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4. A method according to any one of claims 1 to 3, wherein a height of the projected pattern of the insulating layer is 1/10 or more of a thickness of the

layer to be anodically oxidized.

5        5. A method according to any one of claims 1 to 3, further comprising a step of filling a filler in each of the pores after said step of performing anodic oxidation.

10       6. A method according to claim 5, wherein said step of filling a filler is performed by plating.

15       7. A method according to any one of claims 1 to 3, further comprising a step of forming an electrode layer connected to a bottom of each of the pores.

20       8. A structure with pores formed by the method according to any one of claims 1 to 3.

25       9. A structure according to claim 8, further comprising an electrode layer connected to a bottom of each of the pores.

30       10. A method of manufacturing a structure with pores comprising the steps of:

35       (A) sandwiching a film containing aluminum as a main composition between first and second insulating films; and

40       (B) anodically oxidizing the film having aluminum

as the main composition along a direction substantially perpendicular to a direction of making the first and second insulating films face each other,

5 wherein projections are formed on a surface of at least one of the first and second insulating films in contact with the film containing aluminum as the main composition, the projections controlling a pitch between the pores to be formed by anodic oxidation.

10 11. A structure with pores comprising:

(A) a film sandwiched between first and second insulating films, said film containing aluminum oxide as a main composition;

15 (B) a plurality of pores disposed in said film containing aluminum as the main composition, a longitudinal direction of each of said pores being a direction substantially perpendicular to a direction of making said first and second insulating films face each other, and each of said pores being disposed  
20 substantially parallel; and

(C) a projected pattern disposed among said pores, wherein said projected pattern is made of an insulating member in contact with said first or second insulating film and has a line shape substantially  
25 parallel to a longitudinal direction of each of said pores.

12. A structure according to claim 11, wherein said projected pattern is made of a partial region of said first or second insulating film.

13. A structure according to claim 11, wherein said projected pattern is made of a partial region of said first or second insulating film.